PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1 Stylesheet Version v1.2 EPAS ID: PAT3945812

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	SECURITY INTEREST

CONVEYING PARTY DATA

Name	Execution Date
ALPHABET ENERGY, INC.	06/30/2016

RECEIVING PARTY DATA

Name:	ARES CAPITAL CORPORATION
Street Address:	245 PARK AVENUE, 44TH FLOOR
City:	NEW YORK
State/Country:	NEW YORK
Postal Code:	10167

PROPERTY NUMBERS Total: 37

Property Type	Number
Application Number:	12943134
Application Number:	13299179
Application Number:	14567793
Application Number:	13308945
Application Number:	14203360
Application Number:	13331768
Application Number:	14567813
Application Number:	13364176
Application Number:	61438709
Application Number:	13749470
Application Number:	14686641
Application Number:	13760977
Application Number:	13947400
Application Number:	13786090
Application Number:	14333197
Application Number:	14059362
Application Number:	14062803
Application Number:	14053452
Application Number:	14297444
Application Number:	14469404

PATENT REEL: 039064 FRAME: 0828

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Property Type	Number
Application Number:	14707671
Application Number:	14679837
Application Number:	14682471
Application Number:	14872681
Application Number:	14872898
Application Number:	62098945
Application Number:	62129348
Application Number:	62138606
Application Number:	62208954
Application Number:	62216366
Patent Number:	7834264
Application Number:	13430558
Application Number:	61668766
Application Number:	61842842
Patent Number:	8277677
Application Number:	12882580
Application Number:	14823738

CORRESPONDENCE DATA

Fax Number: (949)567-6710

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

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Email: ipprosecution@orrick.com

Correspondent Name: ORRICK, HERRINGTON & SUTCLIFFE LLP/VHS

Address Line 1: 2050 MAIN STREET, SUITE 1100 Address Line 4: IRVINE, CALIFORNIA 92614

ATTORNEY DOCKET NUMBER:	28633.1
NAME OF SUBMITTER:	VICTOR SANTOS
SIGNATURE:	/Victor Santos/
DATE SIGNED:	07/01/2016

Total Attachments: 7 source=Lien#page1.tif source=Lien#page2.tif source=Lien#page3.tif source=Lien#page4.tif source=Lien#page5.tif source=Lien#page6.tif source=Lien#page7.tif

ATTACHMENT 2 TO SECURITY AGREEMENT

GRANT OF SECURITY INTEREST

PATENTS

This GRANT OF SECURITY INTEREST, dated as of June 30, 2016, is executed by Alphabet Energy, Inc., a Delaware corporation ("<u>Grantor</u>"), in favor of Ares Capital Corporation ("<u>Lender</u>").

- A. Pursuant to that certain Loan and Security Agreement, No. V13112 dated as of December 12, 2013 (as amended, supplemented or otherwise modified from time to time, the "Loan Agreement"), between Grantor and Lender and the Fifth Amendment to Loan and Security Agreement dated as of May 1, 2016 (the "Amendment"), Lender agreed to extend loans and other financial accommodations to Grantor upon the terms and subject to the conditions set forth therein.
- B. Grantor owns the letters patent of the United States and certain foreign countries, more particularly described on <u>Schedule 1-A</u> annexed hereto and made a part hereof (collectively, the "<u>Patents</u>").
- C. Grantor and other entities party thereto from time to time have entered into a Security Agreement (Intellectual Property) dated as of June 30, 2016 (as amended, restated, supplemented or otherwise modified from time to time, the "Security Agreement") in favor of Lender.
- D. Pursuant to the Security Agreement, Grantor has assigned and granted to Lender a security interest in all right, title and interest of Grantor in and to the Patents, together with any reissue, continuation, continuation-in-part or extension thereof, and all proceeds thereof, including any and all causes of action which may exist by reason of infringement thereof (the "Collateral"), to secure the prompt payment, performance and observance of the Secured Obligations, as defined in the Security Agreement
- NOW, THEREFORE, for good and valuable consideration, receipt of which is hereby acknowledged, Grantor does hereby further grant to Lender a security interest in the Collateral to secure the prompt payment, performance and observance of the Secured Obligations.

Grantor does hereby further acknowledge and affirm that the rights and remedies of Lender with respect to the security interest in the Collateral granted hereby are more fully set forth in the Security Agreement, the terms and provisions of which are hereby incorporated herein by reference as if fully set forth herein.

The Lender's address is: Ares Capital Corporation 245 Park Avenue, 44th Floor New York, NY 10167

IN WITNESS WHEREOF, the Grantor has caused this Grant of Security Interest to be executed as of the day and year first above written.

GRANTOR

Alphabet Energy, Inc., a Delaware corporation

Name:

Title:

SCHEDULE 1-A TO GRANT OF SECURITY INTEREST PATENTS AND PATENT APPLICATIONS

TITLE	COUNTRY	APPLICATION NO.	STATUS
UNIWAFER THERMOELECTRIC MODULES	US	12/943,134	PENDING
ARRAYS OF LONG NANOSTRUCTURES IN SEMICONDUCTOR MATERIALS	CA	2,818,368	PENDING
ARRAYS OF LONG NANOSTRUCTURES IN SEMICONDUCTOR MATERIALS	CN	201180065569.0	PENDING
ARRAYS OF LONG NANOSTRUCTURES IN SEMICONDUCTOR MATERIALS	EP	11841453.1	PENDING
ARRAYS OF LONG NANOSTRUCTURES IN SEMICONDUCTOR MATERIALS	JP	2013-540036	PENDING
ARRAYS OF LONG NANOSTRUCTURES IN SEMICONDUCTOR MATERIALS	KR	10-2013-7015414	PENDING
ARRAYS OF LONG NANOSTRUCTURES IN SEMICONDUCTOR MATERIALS AND METHODS THEREOF	US	13/299,179	PENDING
ARRAYS OF LONG NANOSTRUCTURES IN SEMICONDUCTOR MATERIALS AND METHODS THEREOF	US	14/567,793	PENDING
LOW THERMAL CONDUCTIVITY MATRICES WITH EMBEDDED NANOSTRUCTURES ,,,	CA	2,819,638	PENDING
LOW THERMAL CONDUCTIVITY MATRICES WITH EMBEDDED NANOSTRUCTURES ,,,	CN	201180066221.3	PENDING
LOW THERMAL CONDUCTIVITY MATRICES WITH EMBEDDED NANOSTRUCTURES ,,,	EP	11845164.0	PENDING
LOW THERMAL CONDUCTIVITY MATRICES WITH EMBEDDED NANOSTRUCTURES ,,,	JP	2013-542193	PENDING
LOW THERMAL CONDUCTIVITY MATRICES WITH EMBEDDED NANOSTRUCTURES ,,,	KR	10-2013-7016783	PENDING
LOW THERMAL CONDUCTIVITY MATRICES WITH EMBEDDED NANOSTRUCTURES AND METHODS THEREOF	US	13/308,945	ISSUED
LOW THERMAL CONDUCTIVITY MATRICES WITH EMBEDDED NANOSTRUCTURES ,,,	US	14/203,360	PENDING
ARRAYS OF FILLED NANOSTRUCTURES WITH PROTRUDING SEGMENTS AND METHODS THEREOF	US	13/331,768	PENDING
ARRAYS OF FILLED NANOSTRUCTURES WITH PROTRUDING SEGMENTS AND METHODS THEREOF	US	14/567,813	PENDING

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TITLE	COUNTRY	APPLICATION NO.	STATUS
ELECTRODE STRUCTURES FOR	CA	2,825,888	PENDING
ARRAYS OF NANOSTRUCTURES ,,,	CA	2,023,000	TENDING
ELECTRODE STRUCTURES FOR	CN	201280016754.5	PENDING
ARRAYS OF NANOSTRUCTURES ,,,			
ELECTRODE STRUCTURES FOR	EP	12790253.4	PENDING
ARRAYS OF NANOSTRUCTURES ,,, ELECTRODE STRUCTURES FOR			
ARRAYS OF NANOSTRUCTURES	JP	2013-552585	PENDING
ELECTRODE STRUCTURES FOR		10 2012 7022500	
ARRAYS OF NANOSTRUCTURES ,,,	KR	10-2013-7022698	PENDING
ELECTRODE STRUCTURES FOR ARRAYS OF NANOSTRUCTURES	РСТ	PCT/US2012/023425	EXPIRED
ARRATS OF NANOSTRUCTURES	101	1 C1/032012/023423	EATIKED
ELECTRODE STRUCTURES FOR	110	10/07/17/	DENTONIC
ARRAYS OF NANOSTRUCTURES ,,,	US	13/364,176	PENDING
STRUCTURE AND METHOD FOR A	US-PRV	61/438,709	EXPIRED
NANOWIRE DEVICE	US-FKV	01/438,709	EAFIRED
MODULAR THERMOELECTRIC		2012212007	DEN ID IN IG
UNITS FOR HEAT RECOVERY	AU	2013212087	PENDING
SYSTEMS MODULAR THERMOELECTRIC			
UNITS FOR HEAT RECOVERY	CA	2,862,350	PENDING
SYSTEMS		2,862,830	TER (BIR (G
MODULAR THERMOELECTRIC			
UNITS FOR HEAT RECOVERY	CN	201380016304.0	PENDING
SYSTEMS			
MODULAR THERMOELECTRIC			
UNITS FOR HEAT RECOVERY	EP	13740495.0	PENDING
SYSTEMS MODULAR THERMOELECTRIC			
UNITS FOR HEAT RECOVERY	US	13/749,470	PENDING
SYSTEMS		13//13,170	LANDING
MODULAR THERMOELECTRIC			
UNITS FOR HEAT RECOVERY	US	14/686,641	PENDING
SYSTEMS			
BULK NANOHOLE STRUCTURES			
FOR THERMOELECTRIC DEVICES	US	13/760,977	PENDING
AND METHODS FOR MAKING THE SAME			
METHOD AND STRUCTURE FOR			
THERMOELECTRIC UNICOUPLE	US	13/947,400	PENDING
ASSEMBLY		,	
BULK NANOPOROUS			
STRUCTURES FOR			_
THERMOELECTRIC DEVICES AND	US	13/786,090	ISSUED
METHODS FOR MAKING THE			
SAME BULK NANO-RIBBON AND/OR			
NANO-POROUS STRUCTURES FOR			
THERMOELECTRIC DEVICES AND	US	14/333,197	PENDING
METHODS FOR MAKING THE		,	
SAME			
NANOSTRUCTURED			
THEMOELECTRIC ELEMENTS	US	14/059,362	ISSUED
AND METHODS OF MAKING THE		2110029000	100011
SAME PHILK SIZE NAMOSTRUCTURED			
BULK-SIZE NANOSTRUCTURED MATERIALS AND METHOD FOR	AU	2013338232	PENDING
MATERIALS AND METHOD FOR			

TITLE	COUNTRY	APPLICATION NO.	STATUS
MAKING			
BULK-SIZE NANOSTRUCTURED			
MATERIALS AND METHOD FOR	CA	2,887,213	PENDING
MAKING		, ,	
BULK-SIZE NANOSTRUCTURED			
MATERIALS AND METHOD FOR	CN	201380062751.X	PENDING
MAKING			
BULK-SIZE NANOSTRUCTURED			
MATERIALS AND METHOD FOR	EP	13852014.3	PENDING
MAKING		1000201110	
BULK-SIZE NANOSTRUCTURED			
MATERIALS AND METHOD FOR	JР	NOT ASSIGNED YET	PENDING
MAKING	"	TOT HOUSE TET	TENEDI (G
BULK-SIZE NANOSTRUCTURED			
MATERIALS AND METHOD FOR	KR	10-2015-7011275	PENDING
MAKING		10-2013-7011273	TENDING
BULK-SIZE NANOSTRUCTURED			
MATERIALS AND METHOD FOR			
MAKING THE SAME BY	US	14/062,803	PENDING
SINTERING NANOWIRES			
STRUCTURES AND METHODS FOR			
	US	14/052 452	PENDING
MULTI-LEG PACKAGE	US	14/053,452	PENDING
THERMOELECTRIC DEVICES			
SILICON-BASED			
THERMOELECTRIC MATERIALS			
INCLUDING ISOELECTRONIC	DOT	DOTE/I 19201 4/041 227	DENDING
IMPURITIES, THERMOELECTRIC	PCT	PCT/US2014/041227	PENDING
DEVICES BASED ON SUCH			
MATERIALS, AND METHODS OF			
MAKING AND USING SAME			
SILICON-BASED	US	14/207 444	DENDING
THERMOELECTRIC MATERIALS	US	14/297,444	PENDING
INCLUDING			
THERMOELECTRIC DEVICES			
HAVING REDUCED THERMAL	D.C.T.	DCT// ICO014/052102	PENDING
STRESS AND CONTACT	PCT	PCT/US2014/053102	PENDING
RESISTANCE, AND METHODS OF			
FORMING AND USING THE SAME			
THERMOELECTRIC DEVICES	110	14460404	TOOLUDE
HAVING REDUCED THERMAL	US	14/469,404	ISSUED
STRESS AND			
THERMOELECTRIC DEVICES	1.0	14505 651	PENDING
HAVING REDUCED THERMAL	US	14/707,671	PENDING
STRESS AND			
FLEXIBLE LEAD FRAME FOR	US	14/679,837	PENDING
MULTI-LEG PACKAGE ASSEMBLY		2,	
FLEXIBLE LEAD FRAME FOR	PCT	PCT/US2015/024484	PENDING
MULTI-LEG PACKAGE ASSEMBLY			
FORMATION AND TRANSFER OF	_	,	_
ULTRA-LONG SILICON	US	14/682,471	PENDING
NANOWIRES			
FORMATION AND TRANSFER OF			
ULTRA-LONG SILICON	PCT	PCT/US2015/024484	PENDING
NANOWIRES			
THERMOELECTRIC GENERATING	US	14/872,681	PENDING
UNIT AND METHODS OF MAKING	PCT	PCT/US2015/053434	PENDING
AND USING SAME	PCI	FC1/US2U13/U33434	FENDING
THERMOELECTRIC GENERATORS	US	14/872,898	PENDING

TITLE	COUNTRY	APPLICATION NO.	STATUS
FOR RECOVERING WASTE HEAT			
FROM ENGINE EXHAUST, AND	PCT	PCT/US2015/053438	PENDING
METHODS OF MAKING AND	FCI	FC1/US2013/033438	FENDING
USING SAME			
ELECTRICAL AND THERMAL			
CONTACTS FOR BULK	US-PRV	62/098,945	PENDING
TETRAHEDRITE			
LOW TEMPERATURE BONDING			
FOR HIGH TEMPERATURE	US-PRV	62/129,348	PENDING
THERMOELECTRIC ASSEMBLIES			
SURFACE PREPARATION AND			
METALLIZATION OF MAGNESIUM	US-PRV	62/138,606	PENDING
SILICIDE-BASED BULK	US-FKV	02/138,000	PENDING
MATERIALS			
ELECTRICAL AND THERMAL			
CONTACTS FOR BULK	US-PRV	62/208,954	PENDING
TETRAHEDRITE MATERIAL			
STRUCTURE AND METHOD FOR			
FLEXIBLE MULTI-UNIT	US-PRV	62/216,366	PENDING
THERMOELECTRIC PACKAGE			
LOW-COST, HIGH RELIABILITY			
PACKAGE ENABLING BONDING			
BETWEEN THERMOELECTRIC	US-PRV		PENDING
MATERIALS, AND METHODS OF			
MAKING THEREOF			
OXIDATION AND SUBLIMATION			
PREVENTION METHOD FOR	US-PRV		PENDING
THERMOELECTRIC DEVICES			
THERMOELECTRIC MATERIAL			
WITH INCREASED MECHANICAL	US-PRV		PENDING
STRENGTH			
ELECTRO-ASSISTED TRANSFER			
AND FABRICATION OF VERTICAL	PCT	PCT/US2013/062022	PENDING
SILICON WIRE ARRAYS	PCI	PC1/US2013/002022	PENDING
(STANFORD LICENSE)			
METHODS OF FABRICATING			
NANOSTRUCTURES AND			
NANOWIRES AND DEVICES	US	7,834,264 B2	ISSUED
FABRICATED THEREFROM			
(NANOSYS LICENSE)			
NANOSTRUCTURED SILICON			
WITH USEFUL THERMOELECTRIC	US	12/420 559	PENDING
PROPERTIES (LBNL [HOLEY	US	13/430,558	PENDING
SILICON] LICENSE)			
NANOSTRUCTURES HAVING			
HIGH PERFORMANCE	PCT	DCT/LIC2000/072022	PENDING
THERMOELECTRIC PROPERTIES	PCI	PCT/US2008/073922	PENDING
(LBNL LICENSE)			
THERMOELECTRIC MATERIALS			
BASED ON TETRAHEDRITE			
STRUCTURE FOR THE	US	61/668,766	PENDING
THERMOELECTRIC DEVICES			
(MSU LICENSE)			
THERMOELECTRIC MATERIALS			
AND METHOD FOR PRODUCING A	HC	61/042 042	DENIDING
THERMOELECTRIC DEVICE (MSU	US	61/842,842	PENDING
LICENSE)			
THERMOELECTRIC MATERIALS	US-PRV		PENDING
	<u> </u>	1	

TITLE	COUNTRY	APPLICATION NO.	STATUS
BASED ON TETRAHEDRITE			
STRUCTURE WITH MODIFIED			
COMPOSITION FOR			
THERMOELECTRIC DEVICES			
(MSU LICENSE)			
IMPROVED MECHANICAL			
STRENGTH AND			
THERMOELECTRIC			
PERFORMANCE IN METAL	US	8,277,677	ISSUED
CHALCOGENIDE MQ (M=GE, SN,			
PB AND Q=S, SE, TE) BASED			
COMPOSITIONS (NWU LICENSE)			
IMPROVED MECHANICAL			
STRENGTH AND			
THERMOELECTRIC			
PERFORMANCE IN METAL	PCT	PCT/US/2008/011550	PENDING
CHALCOGENIDE MQ (M=GE, SN,			
PB AND Q=S, SE, TE) BASED			
COMPOSITIONS (NWU LICENSE)			
THERMOELECTRIC COMPOSITION			
COMPRISING NANOSCALE			
INCLUSIONS IN A	US	12/882,580	PENDING
CHALCOGENIDE MATRIX (NWU			
LICENSE)			
TIN SELENIDE SINGLE CRYSTALS			
FOR THERMOELECTRIC	US	14/823,738	PENDING
APPLICATIONS (NWU LICENSE)			
TIN SELENIDE SINGLE CRYSTALS			
FOR THERMOELECTRIC	PCT	PCT/US2015/044704	PENDING
APPLICATIONS (NWU LICENSE)			

RECORDED: 07/01/2016